

The Electrochemical Society

Magnetic Materials, Processes and Devices 10

at the 214th ECS Meeting

ECS Transactions Volume 16 No.45

October 12-17, 2008
Honolulu, Hawaii, USA

Printed from e-media with permission by:

Curran Associates, Inc.
57 Morehouse Lane
Red Hook, NY 12571
www.proceedings.com

ISBN: 978-1-61567-316-2

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Published by:

The Electrochemical Society
65 South Main Street
Pennington, New Jersey 08534-2839, USA

Telephone 609.737.1902
Fax 609.737.2743
e-mail: ecs@electrochem.org
Web: www.electrochem.org

ISSN 1938-6737 (online)
ISSN 1938-5862 (print)

Printed in the United States of America.

Table of Contents

Preface

Chapter 1 **Electrodeposition in Spin Electronics**

Lab-On-Chip Fabrication of Atomic Scale Magnetic Junctions <i>N. T. Kemp, H. Majjad, P. Lunca-Popa, G. Dalmás and B. Doudin</i>	3
Crystallographic Damage to Mn-Ir Antiferromagnets by Ion Beam Etching <i>K. Watanabe and K. Ueda</i>	11
Extreme Nano-structure Control by Sputtering for the High Density Perpendicular Recording Media and Head <i>M. Takahashi, M. Tsunoda and S. Saito</i>	19
Annealing-Induced Solid-Phase Epitaxy at Interfaces between CoFeB Layers and MgO Barrier-Layer in CoFeB/MgO/CoFeB Magnetic Tunnel Junctions and Their Magnetic Properties <i>Y. Kitamoto, T. Takeuchi, K. Tsunekawa, Y. Choi, Y. Nagamine and D. Djayaprawira</i>	37

Chapter 2 **Patterned Media**

Microstructure of Bit Patterned Media and Recording Characteristics in Perpendicular Magnetic Recording <i>H. Muraoka and Y. Nakamura</i>	47
Electrochemical Fabrication of CoPt Nanodot Arrays on Glass Disks by UV Nanoimprint Lithography <i>T. Ouchi, Y. Arikawa, J. Mizuno, S. Shoji and T. Homma</i>	57
Filling of FePt in AAO Nanohole Array by DC Pulsed Electrodeposition <i>H. Mori, T. Korenaga, N. Hosomi, T. Terui and S. Shingubara</i>	65

Chapter 3

Electrodeposition: Soft and Hard Magnetic Materials

Critical Parameters of Solution Design for Electrodeposition of 2.4 T CoFe Alloys <i>S. R. Brankovic, J. George, S. Bae and D. Litvinov</i>	75
Influence of pH on Electrodeposition and Properties of 2.4T CoFe Alloy <i>J. Gong, S. Riemer, V. Vas'ko, M. Kief and I. Tabakovic</i>	89
Process of CoPt Alloys Electrodeposition for MEMS/NEMS Applications <i>O. Berkh, Y. Shacham-Diamand and E. Gileadi</i>	101
Electrodeposition of Co, Sm and Co-Sm Thin Layers <i>A. Ispas, M. Buschbeck, S. Pitula, A. Mudring, M. Uhlemann, A. Bund and F. Endres</i>	119
DC Aqueous Electrodeposition of Sm-Co Permanent Magnets <i>J. Wei, M. Schwartz and K. Nobe</i>	129
Electrodeposition of an Iron-Cobalt Phase Isostructural to α -Mn <i>B. M. Crozier, Q. Liu and D. Ivey</i>	141
Long Term Investigations on NiFe Electroplating Processes <i>J. Chen, S. Hansen and H. H. Gatzel</i>	155
Effects of Organic Additives on the Residual Stress of Ni and Ni Alloys Electrodeposited from the Sulfamate Bath <i>H. Kim, Y. Kim, S. Lee, J. Lee, M. Lee and Y. Kim</i>	167
Electrodeposition of NiP Film used as a Nonmagnetic Spacer in Laminated (CoFe/NiP) _n Writer Pole <i>M. Sun, S. Riemer, M. Kief and I. Tabakovic</i>	177

Chapter 4

Novel Phenomena and Applications

Controlled Synthesis and Magnetic Properties of Iron Oxide Nanostructures using Biogenic Polyamines <i>S. Shanmugam, T. Nakanishi and T. Osaka</i>	189
Surface Modification of Chemically Synthesized FePt Nanoparticles <i>T. Hachisu, T. Yotsumoto, A. Sugiyama and T. Osaka</i>	199

Investigations on Embedding Nanoparticles by Electroplating <i>M. C. Wurz, T. Oekermann, P. Wagner, C. Ruffert, J. Caro and H. H. Gatzen</i>	207
Electrodeposition of Magnetic Nickel Matrix Nanocomposites <i>A. Bund, C. Gräf, D. Thiemig and C. Kubeil</i>	217
Novel Thermoelectric Cooling of Magnetic Sensors <i>R. Mannam, M. Agarwal, A. Roy, V. Singh, K. Varahramyan and D. Davis</i>	227

Chapter 5

Sensors and MEMS

Magnetic Micro Electro-mechanical Systems for Sensor and Actuator Applications <i>H. H. Gatzen</i>	235
Electroplated Cu Micro Electrode for the Application in Micro Sinking Electro Discharge Machining (Micro-SEDM) <i>H. H. Gatzen, F. Klocke, S. Kamenzky and O. Traisigkhachol</i>	255
A Concept for the Characterization and Analysis of the Permeability of Soft Magnetic Thin-Films <i>O. Traisigkhachol, L. Rissing and H. H. Gatzen</i>	269
Design of a Multiple-Electrode Magnetic-Alloy Plating Cell Using Numerical Modeling <i>P. R. McHugh, G. Wilson, D. Erickson and D. Woodruff</i>	283
Magnetostrictive TMR Sensors for Mechanical Measurements <i>E. Quandt, D. Meyners, T. von Hofe and A. Malavé</i>	297
Author Index	303